

INNOVATION

ANYTHING-ON-ANYTHING

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BIG IDEA CONFERENCE | SEPTEMBER 20th, 2022

DISCLAIMER

This document is provided by Soitec (the "Company") for information purposes only.

The Company's business operations and financial position are described in the Company's 2021-2022 Universal Registration Document (which notably includes the 2021-2022 Annual Financial Report) which was filed on June 20th, 2022, with the French stock market authority (Autorité des Marchés Financiers, or AMF) under number D.22-0523 as well as in the Company's FY'22 half-year report released on December 2nd, 2021. The French versions of the 2021-2022 Universal Registration Document and of the half-year report, together with English courtesy translations for information purposes of both documents are available for consultation on the Company's website (www.soitec.com), in the section Company - Investors - Financial Reports.

Your attention is drawn to the risk factors described in Chapter 2.1 of the Company's 2021-2022 Universal Registration Document.

This document contains summary information and should be read in conjunction with the 2021-2022 Universal Registration Document.

This document contains certain forward-looking statements. These forward-looking statements relate to the Company's future prospects, developments and strategy and are based on analyses of earnings forecasts and estimates of amounts not yet determinable. By their nature, forward-looking statements are subject to a variety of risks and uncertainties as they relate to future events and are dependent on circumstances that may or may not materialize in the future. Forward-looking statements are not a guarantee of the Company's future performance. The occurrence of any of the risks described in Chapter 2.1 of the Universal Registration Document may have an impact on these forward-looking statements. In addition, the future consequences of geopolitical conflicts, in particular the Ukraine / Russia situation, as well as rising inflation, may result in greater impacts than currently anticipated in these forward-looking statements.

The Company's actual financial position, results and cash flows, as well as the trends in the sector in which the Company operates may differ materially from those contained in this document. Furthermore, even if the Company's financial position, results, cash-flows and the developments in the sector in which the Company operates were to conform to the forward-looking statements contained in this document, such elements cannot be construed as a reliable indication of the Company's future results or developments.

The Company does not undertake any obligation to update or make any correction to any forward-looking statement in order to reflect an event or circumstance that may occur after the date of this document. In addition, the occurrence of any of the risks described in Chapter 2.1 of the Universal Registration Document may have an impact on these forward-looking statements.

This document does not constitute or form part of an offer or a solicitation to purchase, subscribe for, or sell the Company's securities in any country whatsoever. This document, or any part thereof, shall not form the basis of, or be relied upon in connection with, any contract, commitment or investment decision.

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SECTION 01

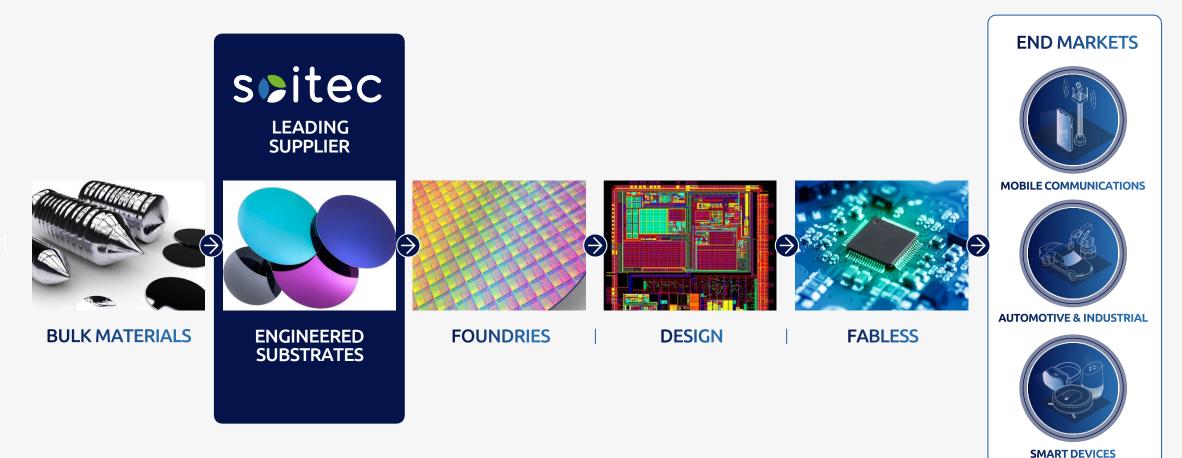
INTRODUCTION TO SOITEC





SOITEC HAS BUILT A UNIQUE POSITION IN THE SEMICONDUCTOR INDUSTRY

LEVERAGING STRATEGIC PARTNERSHIPS IN THE ENTIRE SEMICONDUCTOR ECOSYSTEM



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WE HAVE DEVELOPED A COMPREHENSIVE PRODUCT PORTFOLIO

FOCUSING ON OUR 3 STRATEGIC END MARKETS









SECTION 02

SOITEC INNOVATION STRATEGY





KEY CONTRIBUTORS

TO ENABLE GROWTH



PPAC







Continue Moore's Law

New architectures

New structures / 3D

New materials

New ways to shrink

Advanced packaging

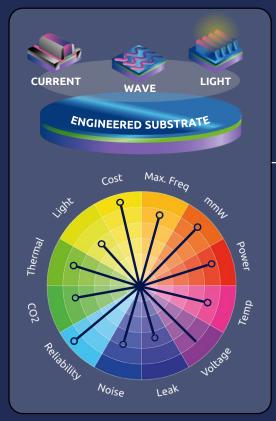






ENGINEERED SUBSTRATES

CREATE VALUE AT THE SYSTEM LEVEL







CONNECT

Data rate, power efficiency

COMPUTE

Energy efficiency performance, data rate with photonics

SENSE

3D imaging, health sensors

POWER

Power density, higher efficiency

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LEVERAGING MATERIALS SCIENCE

TO ENABLE UNIQUE APPLICATIONS

Leverage
MATERIALS INTRINSIC
PROPERTIES

- Electronic
- Photonic
- Piezoelectric
- Electromagnetic

Develop
TECHNOLOGY
SOLUTIONS

- Smart Cut™
- Smart Stacking™
- Epitaxy
- Tiling
- 2.5D/3D
- Surface smoothing
- Smart Cut™ on cavity

Design ENGINEERED SUBSTRATES

- SOI products portfolio
- Anything-on-Anything (Active layer on substrate)

Apply
SEMICONDUCTOR
MEGATRENDS

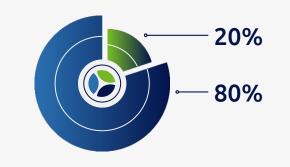
Today:

- 5G
- AI
- Energy efficiency

Tomorrow:

- 6G
- Quantum computing
- Lab on chips

BALANCING SHORT-TERM INNOVATION AND FUTURE OPPORTUNITIES



2022

2026

PRODUCTS UNDER DEVELOPMENT TO SUPPORT OUR BP

TECHNOLOGIES AND PRODUCTS INCUBATION

Addressing short and medium-term differentiations for our customers

INCREMENTAL INNOVATION

SOI next generation

SmartSiCTM

POI next generation

SOI for MEMS

To support future opportunities and growth

DISRUPTIVE INNOVATION

Tiling for large diameters

2.5D/3D

InP - photonics, 6G

Materials science

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Compound integration



2030

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SUBSTRATE INNOVATION CENTER

UNIQUE CAPABILITIES FOR INNOVATIVE SUBSTRATE TECHNOLOGIES





INFRASTRUCTURE

- World class material characterization lab and metrology
- Large choice of equipment/toolset
- Comprehensive material science & engineering

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• On-site dedicated engineers from Soitec

PROGRAMS

- SmartSiC™
- New generation FD-SOI and RF-SOI
- 300mm InP on Si
- Low temperature Smart Cut[™] for 3D integration
- ...

© F. Ardito / CEA

Pilot Line at CEA-Leti for early prototyping of new substrate technologies (focus on lead time and quality)

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SECTION 03

SOITEC INNOVATION TOOLBOX

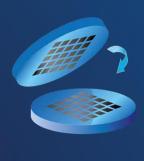




SOITEC CORE TECHNOLOGY TOOLBOX



Smart Cut™



Smart Stacking™



Refresh - Repolish



Epitaxy



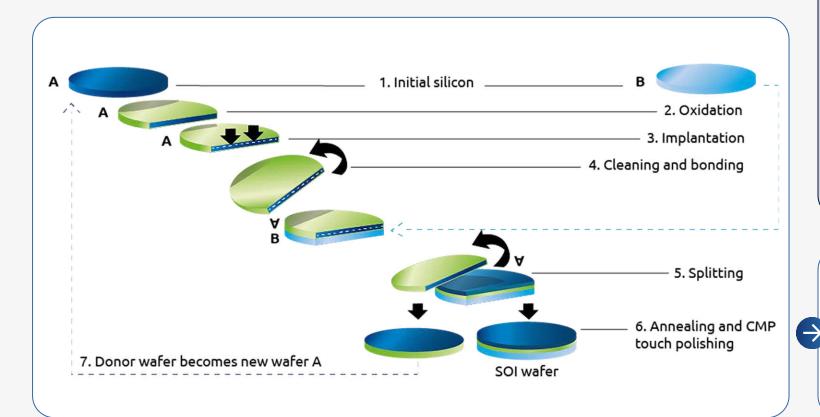
Material Expertise

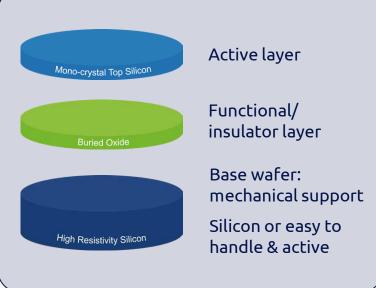


Advanced Processing



SMART CUTTM AND SOI SUBSTRATES





TECHNOLOGY

- Industrial manufacturability of SOI high yield
- Drastic improvement in uniformity & quality
- Re-use of donor wafer increases cost efficiency
- Flexibility of material integration



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VERSATILE SUBSTRATES TECHNOLOGY

OFFERING OUR CUSTOMERS **SUBSTRATE DESIGN** FOR **PERFORMANCE, ENERGY EFFICIENCY, INTEGRATION AND COST BENEFITS** THANKS TO A WIDE RANGE OF OPTIONS TO ENGINEER SUBSTRATES

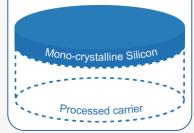
LAYER TRANSFER SOLUTION (SINGLE MATERIAL)

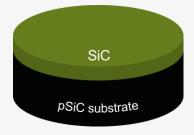
- Material transfer on top of pre-processed wafers
- Sequential manufacturing

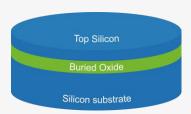
ADDED VALUE SUBSTRATE MATERIALS (APPLICATION SPECIFIC)

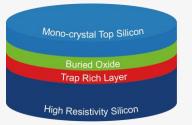
- Conductive bonding capability
- Application-specific active layer with single functional intermediate layer
- Specific layer for handle substrate functionalization
- Complex buried layer stack underneath active layer

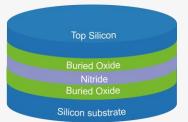
- SUBSTRATES WITH CAVITIES
- Suspended active layer
- Buried cavities
- Versatile buried isolation stack (e.g., SiO₂, Si₃N₄, ONO...)



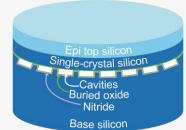








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BEST ACTIVE LAYER(S) ON FUNCTIONAL SUBSTRATE

		ACTIVE LAYER							
		Silicon	Piezo	SiC	InP	GaN	GaAs	Ge	
SUBSTRATE	Silicon								
	Sapphire								
	SiC			1					
S	GaAs								
	Device wafer								

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BEST ACTIVE LAYER(S) ON FUNCTIONAL SUBSTRATE

		ACTIVE LAYER								
		Silicon	Piezo	SiC	InP	GaN	GaAs	Ge		
SUBSTRATE	Silicon	Low power Transistor isolation Radiation hardness Edge AI, 4G/5G, Data Center, Imager	High performance RF filters 4G/5G	Co-integration Quantum	Co-integration Scalable to 300mm High performance 6G, SWIR, Imager	PA performance Co-integration 5G/6G, smartphones	Co-integration Scalable to 300mm Optoelectronics	Co-integration Scalable to 300mm High mobility Optoelectronics		
	Sapphire	Transistor isolation Radiation hardness 3G/4G			Co-integration High performance Optoelectronics	High performance microLEDs	Co-integration High performance Optoelectronics	Co-integration High performance Optoelectronics		
	SiC			Better performance Higher yield Green technologies Power electronics		PA performance Co-integration 5G/6G, baseband				
	GaAs				Optical performance Optoelectronics		Optical performance Optoelectronics			
	Device wafer	Uniformity Crystal quality SoC integration 3D Sequential integration	Uniformity Crystal quality yield Sensors, Actuators							

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FD-SOI – BRINGING AI ONTO THE EDGE WITH LOW ENERGY CONSUMPTION

CHARACTERISTICS Thickness uniformity Micro-roughness Macro-roughness Electrical properties Defectivity Metal contamination Ultra Thin top Silicon layer Thickness uniformity Ultra-Thin Buried Oxide • Parasitic charges Integrity Handle Si • (Breakdown voltage) Geometry Bulk micro defects Metal contamination



SUBSTRATE

IMPACT ON DEVICE



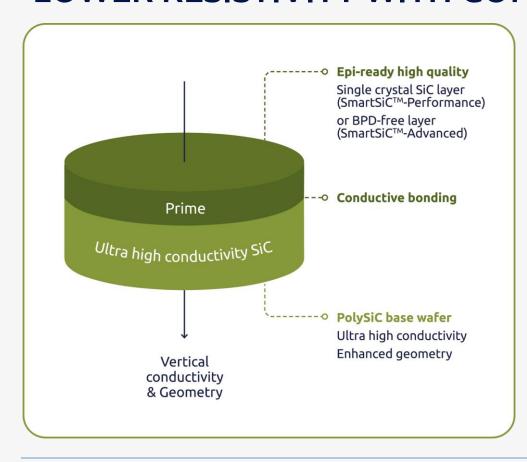
SYSTEM BENEFITS

- Electrostatics
- Variability
- Mobility
- Yield
- Electrostatics
- Back gate control
- Variability
- Reliability
- Variability
- Yield

Low power

- Easy digital/analog RF integration
- Ultra-low leakage
- Cost effective (simpler processing)
- Robust energy harvesting 'zero power' capabilities

SMARTSICTM – BONDING 2 DIFFERENT SUBSTRATES ALLOWS FOR LOWER RESISTIVITY WITH CONSTANT DEFECTIVITY



VALUE PROPOSITION

SmartSiC™vs. SiC: Greener, Faster and Better

- 20,000 Tons of CO₂ reduction for each 500,000 wafers vs. SiC
- 200mm scalability to accelerate SiC adoption through 10x reusability
- Enabling new generations of SiC devices thanks to an improvement of resistivity of up to 30%
- Reducing Capex & Opex for device manufacturers

ANYTHING ON ANYTHING AS A PERFORMANCE CATALYST

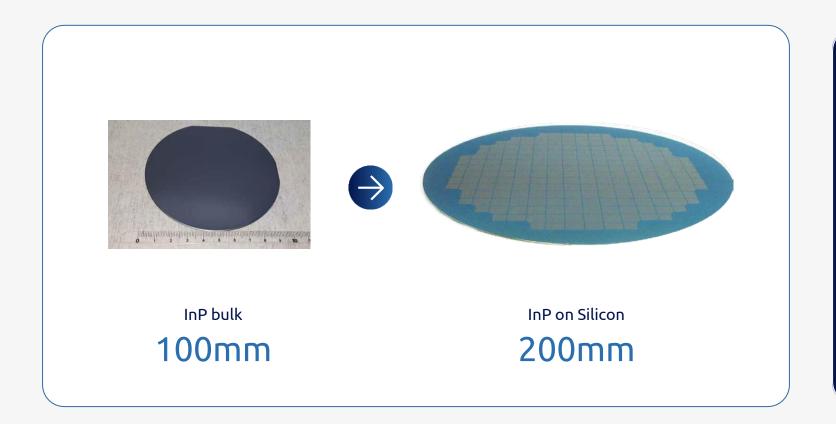
- Significant improvement of resistivity through doping while maintaining low defectivity
- Prime layer of single-crystal SiC, with very low doping and high quality crystal, has a minimal contribution to vertical conductivity given thinness
- Thicker Ultrahigh-conductivity SiC (polySiC) layer can be properly doped without affecting crystal quality

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TILING - EXAMPLE WITH InP



ENABLING InP FOR SEVERAL APPLICATIONS

- High frequency devices (RF, THz, 5G/6G, ...)
- Optoelectronics & Photonics (lasers, 3D sensing, PICs, gas sensing, ...)
- SWIR Image sensors
- Energy harvesting (IR, solar cells, ...)

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InP SUBSTRATE TECHNOLOGIES FOR RF APPLICATIONS

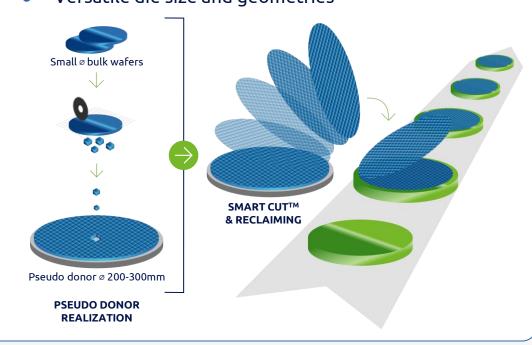
Smart CutTM "InP-on-Anything"

- Handle substrate: Silicon, GaAs,...
- Donor substrate reclaiming
- but limited to 4-6 in diameter



Tiling for InP

- Scaling to larger wafer diameter (up to 12in)
- Handle substrate: Silicon (bulk or device wafer)
- Versatile die size and geometries



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TOWARDS HIGH DENSITY 3D DEVICE STACKING

3D Integration benefits

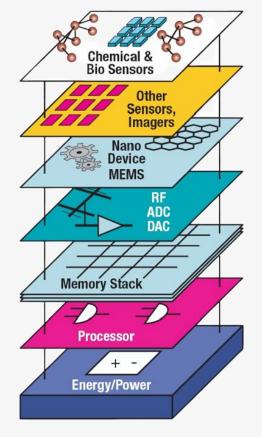
- Higher performance and density
- Higher functionality
- Smaller form factor
- Cost reduction

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3D Monolithic adds further value

- Front end device integration
- Very dense device integration by nm alignment

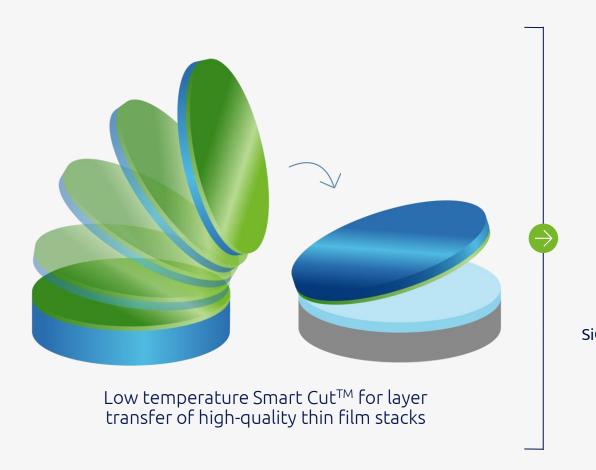




Courtesy of Pr. James J.-Q. Lu, IEEE fellow A New Paradigm for Future Technologies



3D LAYER STACKING BY SMART CUT™



Front-end processed wafer with devices (or/and back-end with Mx, My)

e.g., CMOS, DRAM, etc



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INNOVATION TAKEAWAYS

INNOVATION AT THE HEART OF SOITEC SUSTAINABLE VALUE CREATION MODEL

- We are transforming our Innovation to meet short to longterm market needs
- Our Innovation is enabling 20-25% annual growth towards ~2.3bn revenue in FY26

ENGINEERED SUBSTRATES AND SEMICONDUCTOR INNOVATION

- Leveraging materials science through engineered substrates
- PPACt is driving our innovation strategy
- SmartSiC[™] technology demonstrated, actively working on prototyping and qualifying with several customers

SOITEC INNOVATION MODEL

- Maturing & sharpening our technologies to bring best layer on best substrate
- Strengthening our collaboration model
- Developing products fitted for High Volume Manufacturing





THANK YOU

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